

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	44956	"438"/\$.ccls. and laser adj2 ablationsame UV adj2 radiation	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/05/02 10:44
L2	8	"438"/\$.ccls. and laser adj2 ablation same UV adj2 radiation	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/02 10:31
L3	1101	"438"/\$.ccls. and electron adj2 beam adj2 lithography	US-PGPUB; USPAT	OR	ON	2007/05/02 10:46
L4	18	"438"/\$.ccls. and laser adj beam adj interference	US-PGPUB; USPAT	OR	ON	2007/05/02 10:53
L6	167	"438"/\$.ccls. and laser adj2 ablation with mask	US-PGPUB; USPAT	OR	ON	2007/05/02 10:54
L8	8	"438"/\$.ccls. and UV adj2 radiation with mask with laser	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/02 11:04
L13	2103	UV adj2 radiation with laser	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/02 11:07
L14	86	UV adj2 radiation with laser with mask	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/02 11:22
L15	34	pattern\$3 with (mask film) with UV adj radiation with laser	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/02 11:33

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L25	46	electron adj2 beam adj2 lithography with laser adj2 ablation	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/02 12:07
L26	2103	UV adj2 radiation with laser	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/02 12:07
L27	107	UV adj2 radiation with laser with pattern\$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/02 13:17
L29	4244	emboss\$3 same laser	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/05/02 13:56
L30	76	emboss\$3 same laser same template	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/02 13:59
L31	3	emboss\$3 with mask and laser with template	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/02 14:04
L32	224	emboss\$3 with mask and laser	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/02 14:31

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L34	436	etch adj2 (ratio rate) same mask same shape	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/02 15:01
L38	14087	light adj2 emitting adj2 (diode device chip) and metal with aluminum	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/02 15:06
L39	1097	light adj2 emitting adj2 (diode device chip) same metal with aluminum	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/05/02 15:06